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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Peter J. de Groot  
Serial No. : 10/659,060  
Filed : September 9, 2003  
Title : INTERFEROMETRY METHOD FOR ELLIPSOMETRY, REFLECTOMETRY,  
AND SCATTEROMETRY MEASUREMENTS, INCLUDING  
CHARACTERIZATION OF THIN FILM STRUCTURES

Art Unit : 2877  
Examiner : Marissa Detschel

**Mail Stop Amendment**  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

AMENDMENT IN REPLY TO ACTION OF MARCH 14, 2006

Please amend the above-identified application as follows:

CERTIFICATE OF MAILING BY FIRST CLASS MAIL

I hereby certify under 37 CFR §1.8(a) that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and is addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

6-6-06  
Date of Deposit

*Cheryl A. Forrest*  
Signature

CHERYL A. FORREST  
Typed or Printed Name of Person Signing Certificate